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| · | Application No. | Applicant(s) |
| Alada a f Alla a al III a | 10/665,934 | LIU ET AL. |
| Notice of Allowability | Examiner | Art Unit |
| | Brook Kebede | 2823 |
| The MAILING DATE of this communication appears on the cover sheet with the correspondence address All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS. This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308. | | |
| 1. This communication is responsive to 10 January 2005. | | |
| 2. The allowed claim(s) is/are <u>1,2,4-16,18 and 19</u> . | | |
| 3. The drawings filed on 19 September 2003 are accepted by the Examiner. | | |
| 4. Acknowledgment is made of a claim for foreign priority unal All b) Some* c) None of the: 1. Certified copies of the priority documents have 2. Certified copies of the priority documents have 3. Copies of the certified copies of the priority documents have linternational Bureau (PCT Rule 17.2(a)). * Certified copies not received: | be been received. be been received in Application No | |
| Applicant has THREE MONTHS FROM THE "MAILING DATE" noted below. Failure to timely comply will result in ABANDONM THIS THREE-MONTH PERIOD IS NOT EXTENDABLE. | | complying with the requirements |
| 5. A SUBSTITUTE OATH OR DECLARATION must be submitted. Note the attached EXAMINER'S AMENDMENT or NOTICE OF INFORMAL PATENT APPLICATION (PTO-152) which gives reason(s) why the oath or declaration is deficient. | | |
| 6. CORRECTED DRAWINGS (as "replacement sheets") mus | st be submitted. | |
| (a) ☐ including changes required by the Notice of Draftsperson's Patent Drawing Review (PTO-948) attached | | |
| 1) 🗌 hereto or 2) 🔲 to Paper No./Mail Date | | |
| (b) ☐ including changes required by the attached Examiner's Amendment / Comment or in the Office action of Paper No./Mail Date | | |
| Identifying indicia such as the application number (see 37 CFR 1 each sheet. Replacement sheet(s) should be labeled as such in t | .84(c)) should be written on the drawir he header according to 37 CFR 1.121(c | ngs in the front (not the back) of d). |
| 7. DEPOSIT OF and/or INFORMATION about the depo attached Examiner's comment regarding REQUIREMENT | sit of BIOLOGICAL MATERIAL r FOR THE DEPOSIT OF BIOLOGIC | nust be submitted. Note the AL MATERIAL. |
| Attachment(s) 1. Notice of References Cited (PTO-892) | 5. ☐ Notice of Informal P | atent Application (PTO-152) |
| 2. Notice of Draftperson's Patent Drawing Review (PTO-948) | 6. Interview Summary | (PTO-413), |
| 3. Information Disclosure Statements (PTO-1449 or PTO/SB/0 Paper No./Mail Date 1/10/05 4. Examiner's Comment Regarding Requirement for Deposit of Biological Material | <u> </u> | |
| | | |

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EXAMINER'S AMENDMENT

1. An examiner's amendment to the record appears below. Should the changes and/or

additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR

1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the

payment of the issue fee.

Authorization for this examiner's amendment was given in a telephone interview with

Ms. Lie-Yea Cheng on February 16, 2005.

2. The application has been amended as follows:

In the Claims:

Please cancel Claim 3.

Change Claim 1 to:

-- A method for trimming photoresist features on a semiconductor substrate in a plasma

processing system, comprising: placing a substrate with a patterned photoresist layer having at

least one element with a first prescribed width on the substrate in the plasma processing system;

supplying to the process chamber a process gas mixture comprising a hydrocarbon gas, an

oxygen gas, and an inert gas, or a process gas mixture comprising a halogenated

hydrocarbon gas, an oxygen gas, and an inert gas, or a mixture the safe and disassociating

the process gas mixture to etch the patterned photoresist layer.---.

Change Claim 4 to:

-- The method of claim 1 wherein the halogenated hydrocarbon gas is CHF₃.--.

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Allowable Subject Matter

3. Claims 1, 2, 4-16, 18 and 19 are allowed over prior art of record.

Reasons for Allowance

4. The following is an examiner's statement of reasons for allowance:

The prior art of record neither anticipates nor renders obvious the claimed subject matter of the instant application as a whole either taken alone or in combination, in particular, prior art of record does not teach "supplying to the process chamber a process gas mixture comprising a hydrocarbon gas, an oxygen gas, and an inert gas, or a process gas mixture comprising a halogenated hydrocarbon gas, an oxygen gas, and an inert gas, or a mixture thereofs; and disassociating the process gas mixture to etch the patterned photoresist layer," as recited in claim 1.

Claims 2, 4-16, 18 and 19 are also allowed as being directly or indirectly dependent of the allowed independent claim.

Conclusion

5. Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Correspondence

6. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Brook Kebede whose telephone number is (571) 272-1862. The examiner can normally be reached on 8-5 Monday to Friday.

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If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Olik Chaudhuri can be reached on (571) 272-1855. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

BK February 16, 2005

George Fourson

Primary Examiner